国仪量子
CIQTEK

Focused Ion Beam-Scanning Electron Microscope (FIB-SEM) DB500

Electron Beam System	Gun type	High brightness Schottky Plus Field Emission Electron Gun
	Resolution	1.2 nm@15 kV
	Acceleration voltage	20 V ~ 30 kV
Ion Beam System	Ion source type	Liquid gallium ion source
	Resolution	3 nm@30 kV
	Acceleration voltage	500 V ~ 30 kV
Sample Chamber	Vacuum system	Fully automatic control, oil-free vacuum system
	Camera	Triple camera (Optical navigation + sample chamber monitoring x2)
	Sample stage type	Eucentric stage
	Sample stage travel	X=110 mm，Y=110 mm，Z=65 mm T: -10° ~+70°，R: 360°
Detector and Extension	Standard	Inlens ETD
	Optional	STEM EDS EBSD Nanomanipulator Gas injection plant Plasma cleaning Sample fast exchange chamber Trackball & knob control panel
Software	Language	English
	OS	Windows
	Navigation	Optical navigation, gesture quick navigations
	Automatic function	Auto brightness contrast, auto focus, auto astigmatism